

Supplementary data

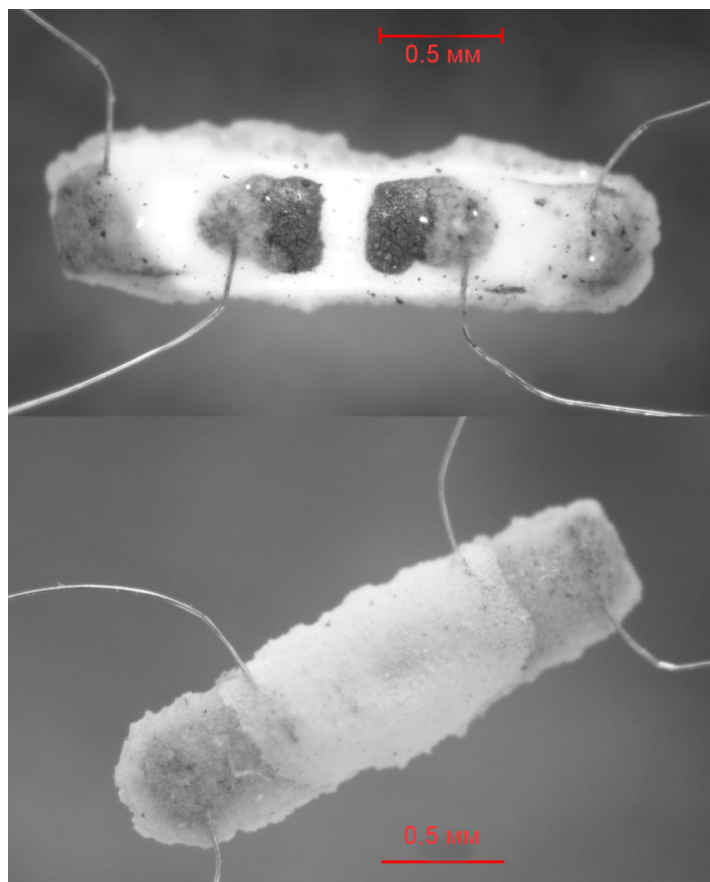


Figure S1. Microscope images of sensor substrate before (top) and after (bottom) thick film deposition.

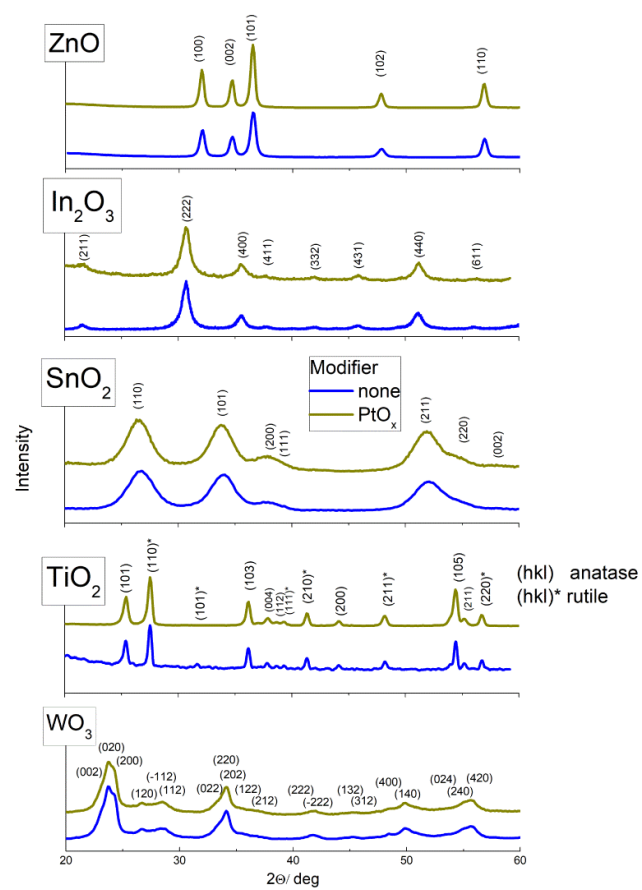


Figure S2. XRD patterns of MOS and MOS/PtO_x samples.

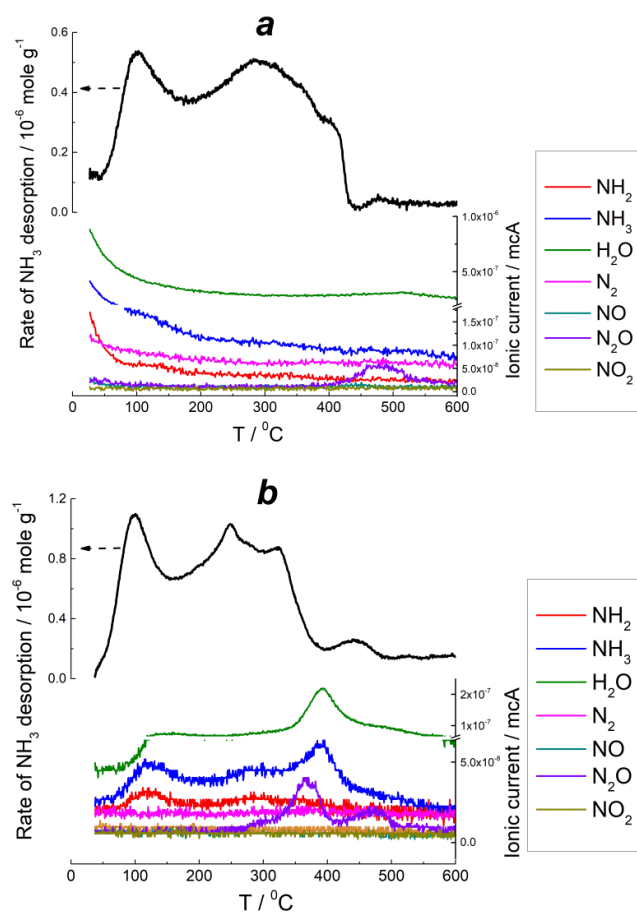


Figure S3. Patterns of ammonia TPD from the surface of MOS (thermal conductivity detector, TCD) and mass-spectrometric analysis (MS) of desorbed gas.

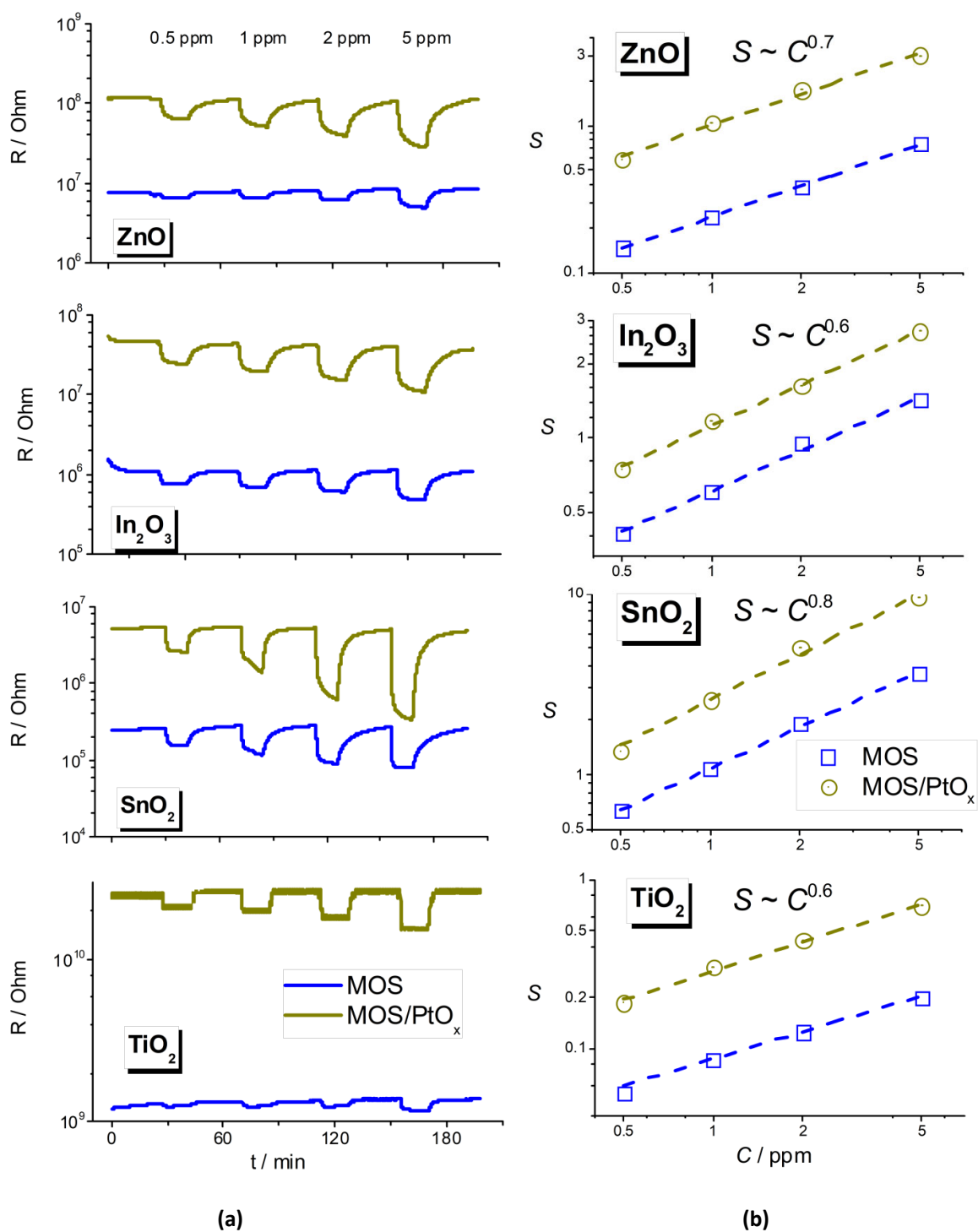


Figure S4. Dynamic response of pristine and PtO_x-modified ZnO, In₂O₃, SnO₂, and TiO₂ to 0.5–5 ppm benzene at 220 °C (a), sensor signals in relation to benzene concentration at 220 °C (b).